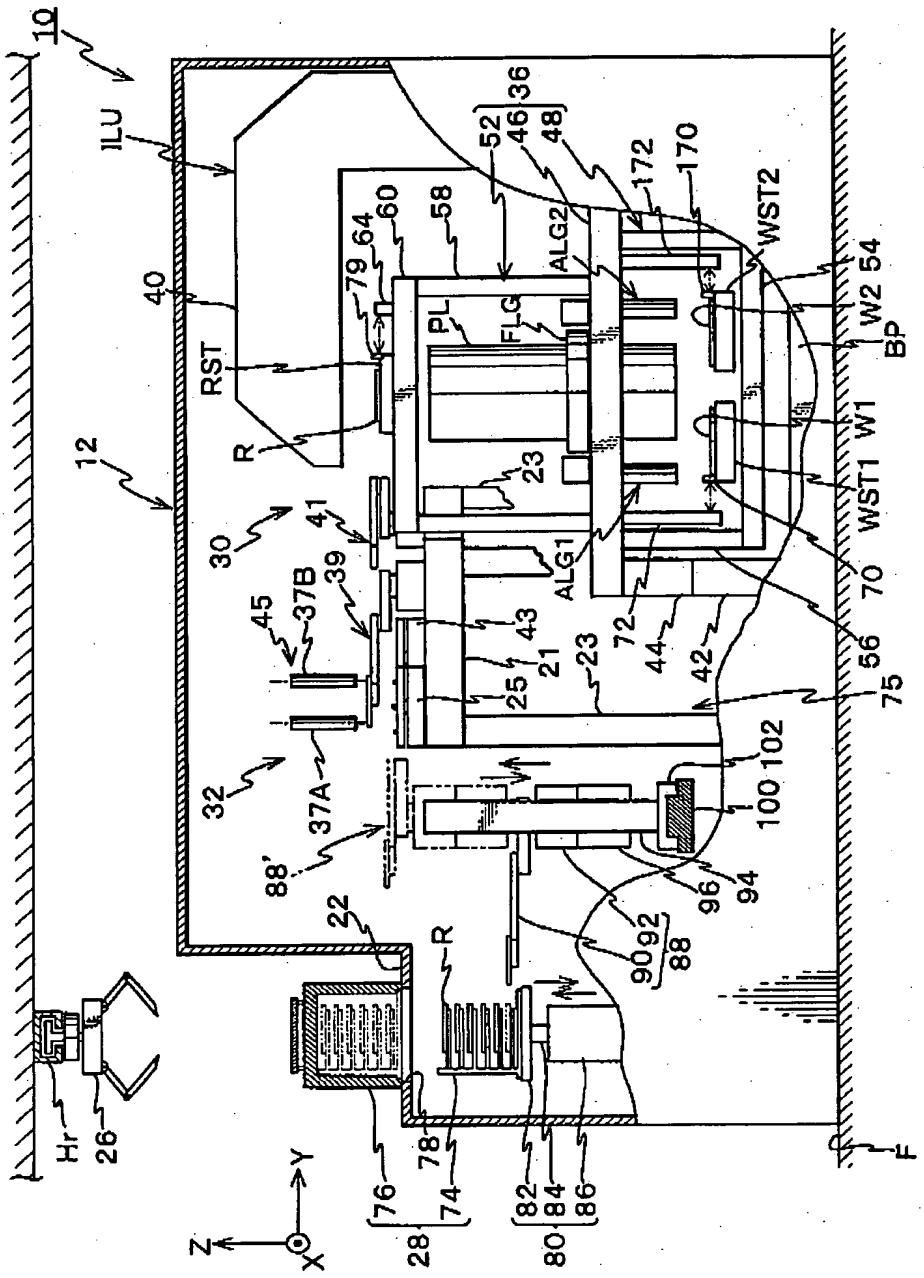

10
ILU
12
40
RST
R
30
41
39
37B
45
43
21
25
23
32
37A
88'
22
R
Hr
26
76
78
74
28
82
84
86
80
Y
Z
X
52
46
48
36
172
170
WST2
54
W2
BP
W1
WST1
70
56
75
72
44
42
102
100
94
96
92
90
88
ALG2
ALG1
PL
FLG
64
79
60
58
23

Fig. 1

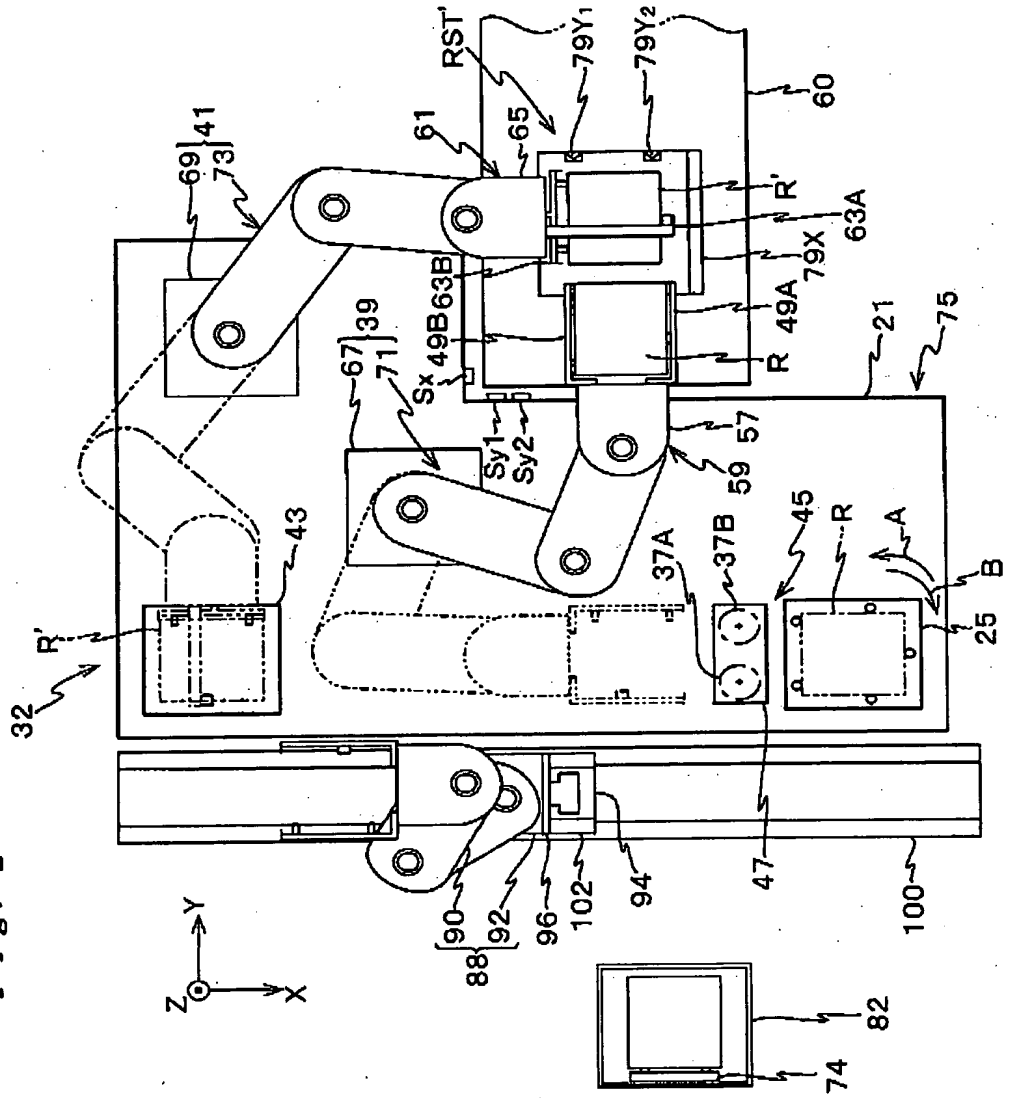

RST'
79Y1
79Y2
60
61
65
41
69
73
R'
63A
79X
63B
49A
R
49B
Sx
39
67
71
21
75
Sy1
Sy2
57
59
43
45
R
A
B
37A
37B
25
R'
32
47
100
90
92
88
96
102
94
82
74
Y
Z
X

Fig. 2

*Fig. 3*

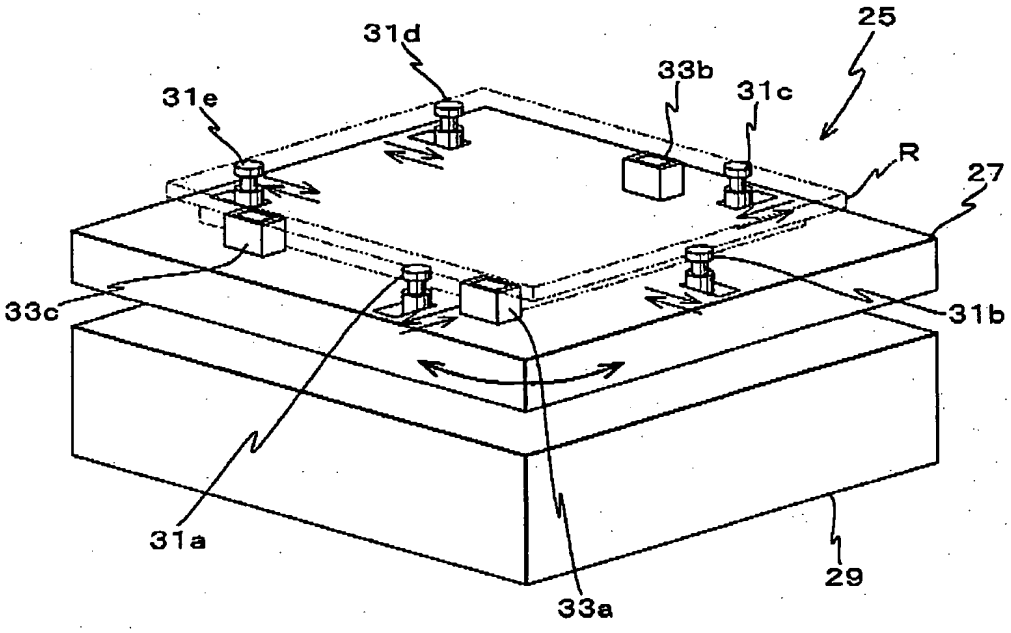


*Fig. 4A*

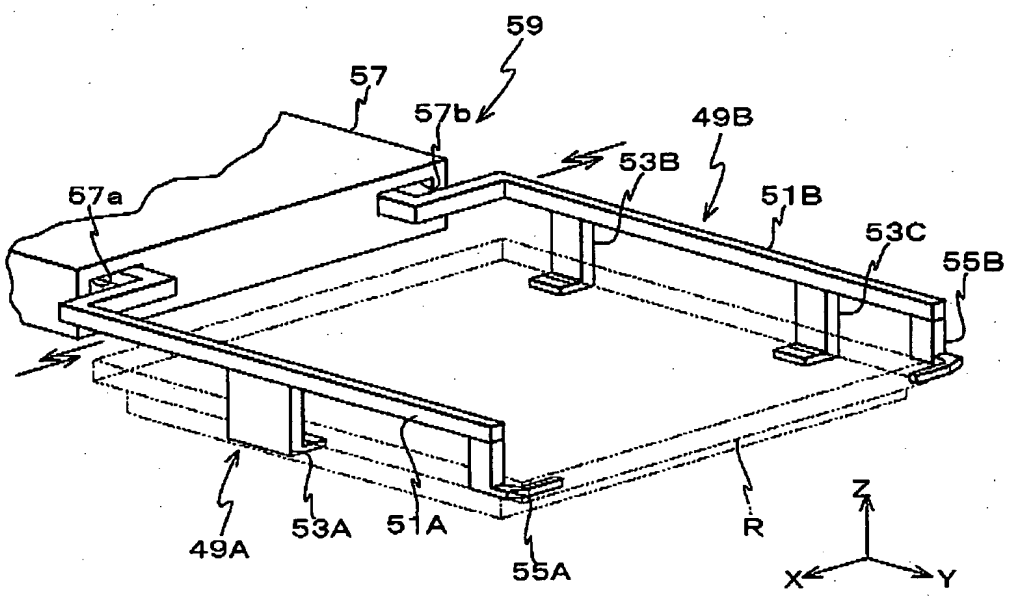

59
57
57b
49B
53B
57a
51B
53C
55B
49A
53A
51A
55A
R
Z
X
Y

*Fig. 4B*

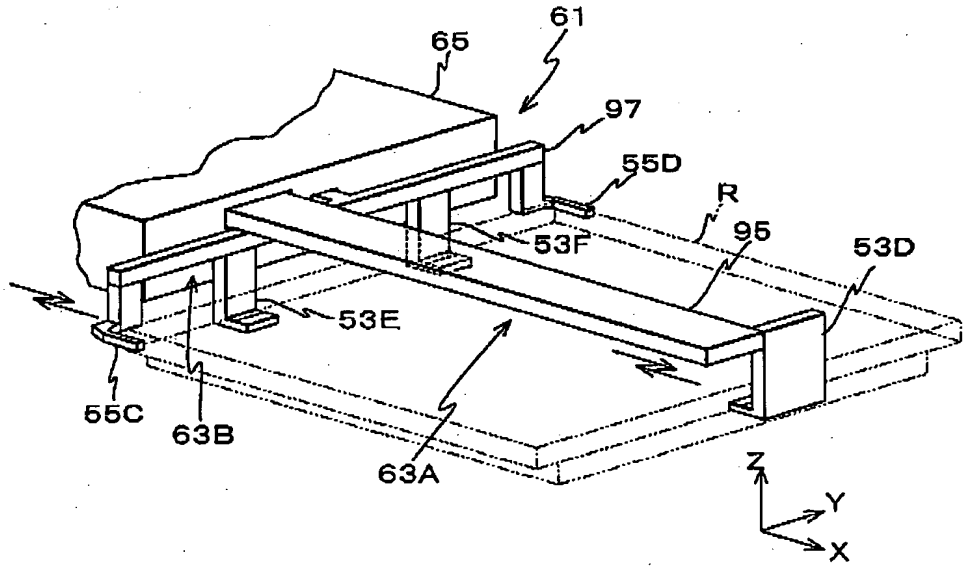

61
65
97
55D
R
95
53F
53D
53E
55C
63B
63A
Z
Y
X

*Fig. 5*

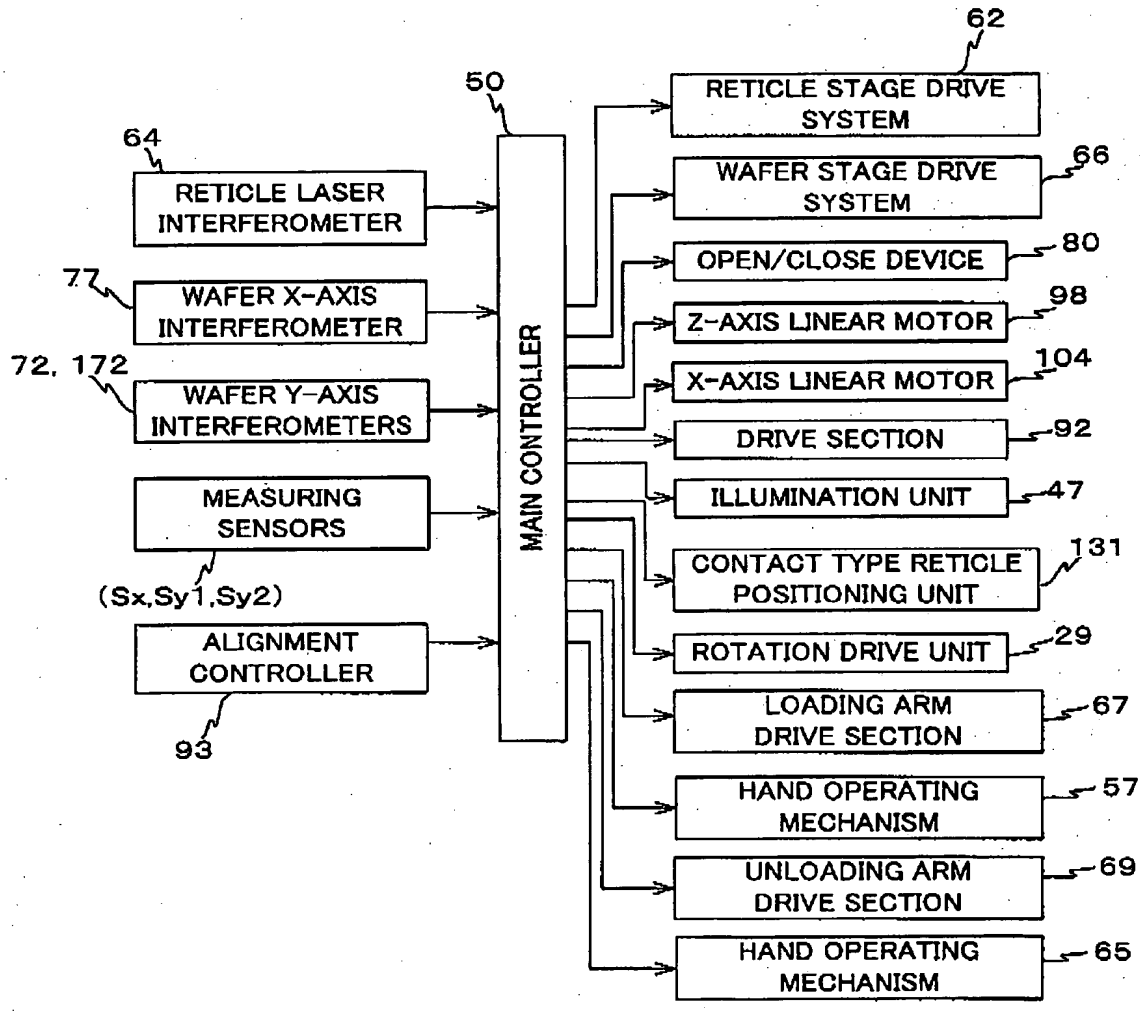

62
50
RETICLE STAGE DRIVE SYSTEM
64
RETICLE LASER INTERFEROMETER
WAFER STAGE DRIVE SYSTEM
66
OPEN/CLOSE DEVICE
80
77
WAFER X-AXIS INTERFEROMETER
Z-AXIS LINEAR MOTOR
98
72, 172
WAFER Y-AXIS INTERFEROMETERS
X-AXIS LINEAR MOTOR
104
DRIVE SECTION
92
MEASURING SENSORS
ILLUMINATION UNIT
47
MAIN CONTROLLER
CONTACT TYPE RETICLE POSITIONING UNIT
131
(Sx,Sy1,Sy2)
ROTATION DRIVE UNIT
29
ALIGNMENT CONTROLLER
LOADING ARM DRIVE SECTION
67
93
HAND OPERATING MECHANISM
57
UNLOADING ARM DRIVE SECTION
69
HAND OPERATING MECHANISM
65

*Fig. 6A*

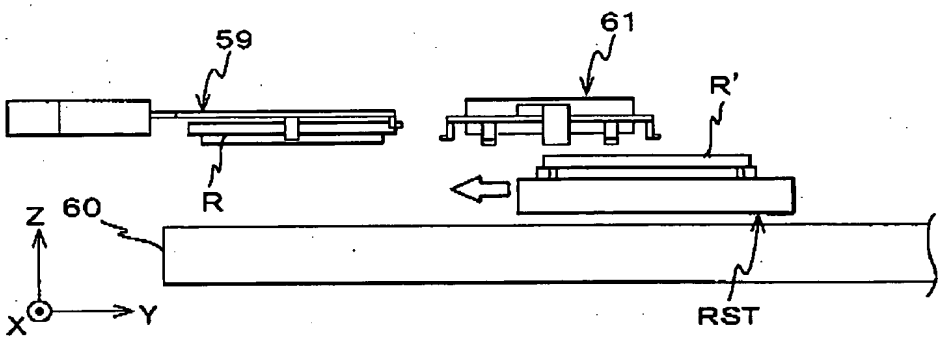



*Fig. 6B*

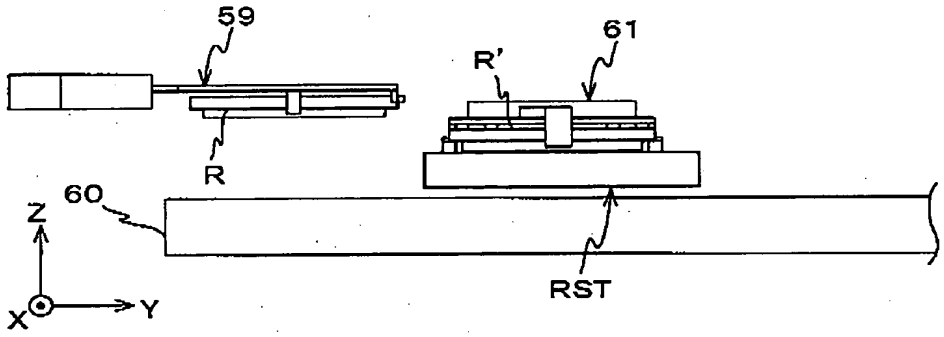



*Fig. 6C*

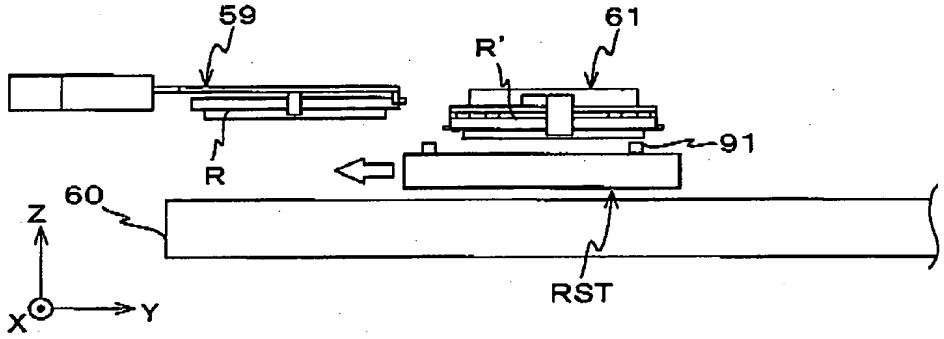


*Fig. 7A*

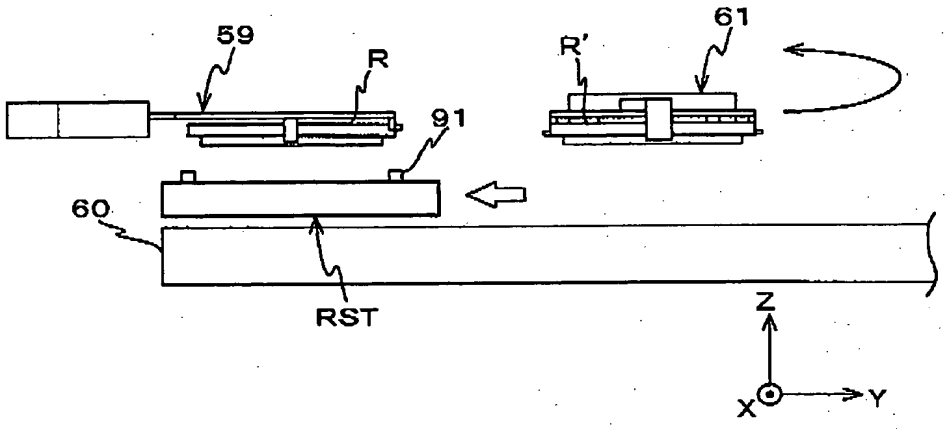



*Fig. 7B*

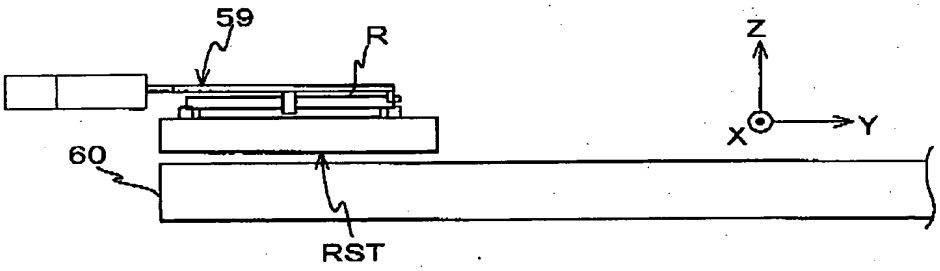
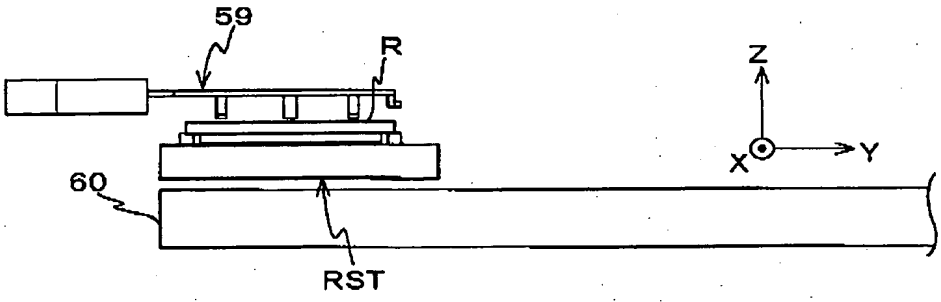



*Fig. 7C*



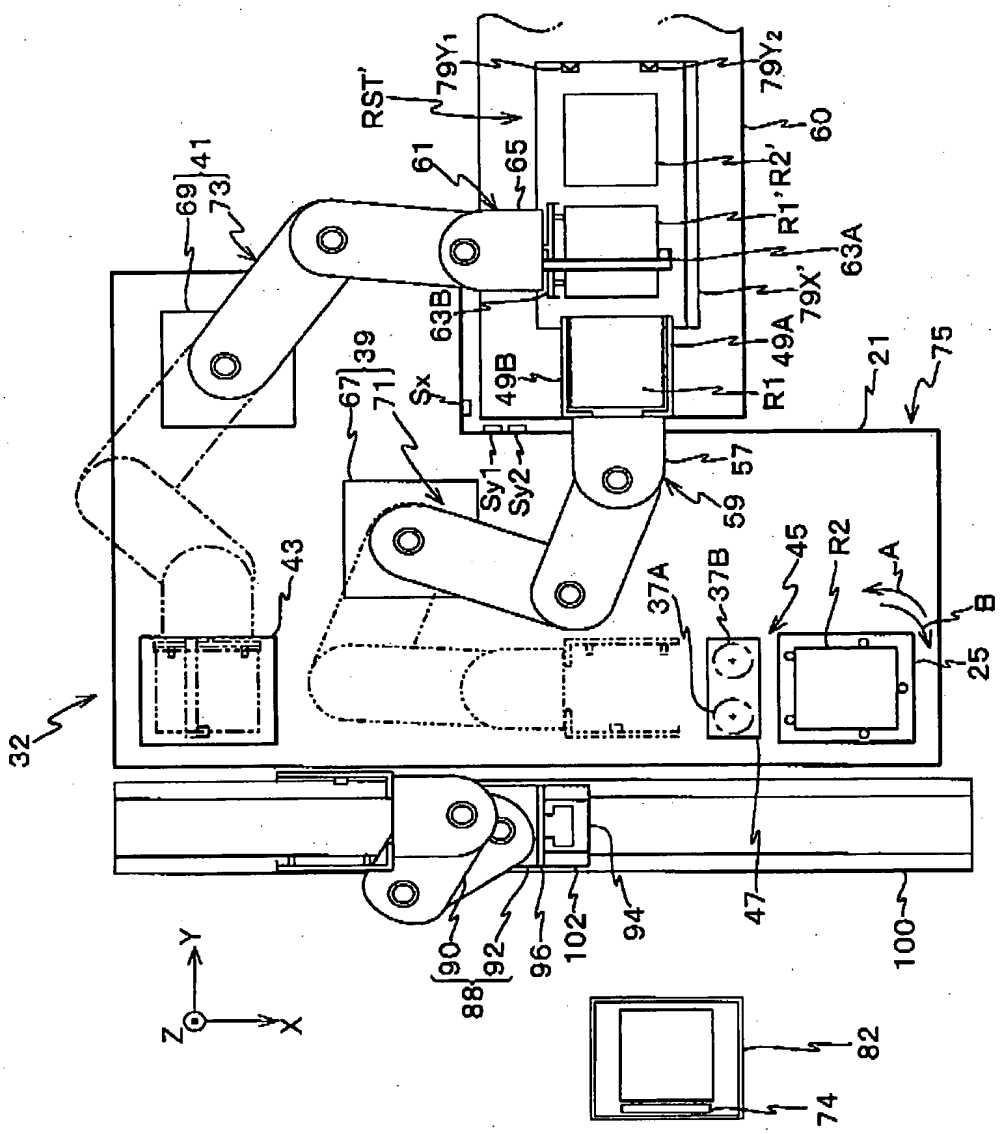

RST'
79Y1
79Y2
60
61
65
69
41
73
R1'R2'
63A
79X'
63B
49A
R1
49B
39
67
71
Sx
21
75
Sy1
Sy2
57
59
43
37A
37B
45
R2
A
B
25
32
47
100
90
88
92
96
102
94
82
74
Y
Z
X

Fig. 8

*Fig. 9*

PRIOR ART

